Equipment Information Sheet KOH Hood and Bath

Manager:	Christopher Alpha	607-254-4913	Calls to staff phones will be automatically forwarded to their cell phones during accessible hours. At other times leave a message or send them an email.
Backup:	Aaron Windsor	607-254-4831	

## **SAFETY**

- All standard lab policies apply
- FULL PPE green gloves, apron, face shield
- Keep tank closed except when loading and unloading

#### **USAGE RESTRICTIONS**

• Normal buddy system rules in effect

## SCHEDULING/SIGN-UP RESTRICTIONS

- 4 hours from 8am to 6pm, M-F
- 12 hours between 6pm and 8am, M-F and weekends

# MATERIALS COMPATIBILITY CATEGORY

Minimum Tool Time: 30 minutes

### Tool Category 1E: Silicon Based Materials and Select Dieletrics

Allowed	Not Allowed			
Silicon Based Materials only	No Evaporated or Sputtered Films			
Si, SiC, SiO <sub>2</sub> substrates	No Metal or Organic Films			
All Furnace grown or deposited films	No Glass Substrates			
PECVD Films	No III/V Compound Semiconductors			
Select ALD dieletrics (SiO <sub>2</sub> , SiN, HfO <sub>2</sub> , HFN)	No High Vapor pressure materials			
Spin on Glass and Spin on Dopants	Organic/Biology Molecules prepared-with or without Salt buffers			

High Vapor Pressure Metals and Compounds are materials that have a vapor pressure above 1e-6 Torr at 400 C.

# Additional Material Restrictions and Exceptions

- Si substrates only
- SiN masks only

Last Updated: 11/29/2018